



GlobalWafers Co., Ltd.
環球晶圓股份有限公司

**Global Family,
Global Solutions!**

**A Dive Into Various Wafer
Types for RF Optimal
Performance**

Bruno Baccus

26/04/2024

Incize 10-year Anniversary Event



RF Applications and Link to Wafer Options

- RF space offers interesting connections between the initial condition (wafers) and the final application
- Wafer characteristics -> RF performance (ex: high frequency, harmonics) -> System integration -> final device (ex: 5G smartphone)
- This is why the initial wafer material, design and characteristics are of specific importance besides usual requirements (doping, flatness...)

RF semiconductor materials



Material	Advantages	Applications
Silicon (Si) CZ FZ SOI	Low cost & Ease of fabrication : Si is abundant and cost-effective	RF switches Low-power RF applications
	Si-based devices can be manufactured using mature CMOS technology.	IoT devices Consumer electronics
	Integration: Si allows integration of digital and analog circuits on a single chip	High Frequency CMOS Even higher frequency with SiGe HBT integrated with CMOS
Gallium Nitride (GaN)	Wide bandgap: GaN has a larger bandgap than GaAs, allowing it to operate at higher temperatures.	RF power amplifiers (especially in 5G networks) Radar systems Satellite communication Base stations
	High breakdown voltage: GaN devices can handle high voltages	
	High electron mobility: GaN transistors are used in power amplifiers for wireless communication	
Gallium Arsenide (GaAs)	High electron mobility: GaAs exhibits excellent electron transport properties, making it suitable for high-frequency applications	RF filters LNAs Power amplifiers
	Low noise figure: GaAs-based devices are commonly used in low-noise amplifiers (LNAs) for sensitive RF receivers	Switches Phase shifters
	High power handling capability: GaAs power amplifiers are prevalent in RF communication systems.	Oscillators Antenna tuners
LT and LN wafer substrate: LiTaO3 (Lithium Tantalate, LT) and LiNbO3 (Lithium Niobate, LN)	Multi-function crystal material which possess unique optical, piezoelectric and pyroelectric properties	Wi-Fi, 4G, 5G, GPS and also use on device for high speed fiber-optic communication
	LT and LN are widely applicable in wireless communication field	
Silicon Carbide (SiC) Semi-Insulating SiC GaN on Si-SiC	High-temperature operation: SiC devices can withstand extreme temperatures.	High-power RF amplifiers
	High breakdown voltage: SiC is used in high-power applications.	Harsh environment applications (e.g., aerospace, automotive)
	Excellent thermal conductivity: SiC dissipates heat efficiently.	Wireless power transfer

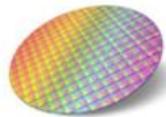


SAS Strategic Layout of Key Areas





GWC has the world largest wafer product portfolio



	Wafer Diameter (mm)			End-applications				
	LE150	200	300					
Annealed Wafer		✓	✓	 Memory	 LCD Driver	 Analog/Logic IC		
EPI Wafer (Epitaxial)	✓	✓	✓	 Power Device	 Automobile	 MPU/MCU	 CMOS Image Sensor	
Polished Wafer	✓	✓	✓	 Communication	 Power Device	 Analog/Logic IC	 Memory	
Diffused Wafer	✓			 Automobile	 Electricity	 Aerospace		
Non-polished Wafer	✓			 Discrete Device				
FZ Wafer (Float Zone)	✓	✓		 Medical Equipment	 Wind Turbine	 High Speed Rail	 Automobile	
SOI Wafer (Silicon on Insulator)	✓	✓	✓	 High Voltage Power	 MEMS Sensor	 CMOS	 RF Device	 Photonics
SiC Wafer (Silicon Carbide)	✓	✓		 Automobile	 High Voltage Power	 High Speed Rail	 Wind Turbine	
GaN/Si, GaN/SiC (Gallium Nitride)	✓	✓		 Solar Inverter	 Power Supplies	 RF Power		



Polished Wafers – CZ Silicon

- (100) lightly doped wafers
 - 10's-100's ohm-cm for SiGe technology
 - >1000 ohm-cm for passives (high-Q inductors)
- CZ Crystal Growth
- Less demanding design rules / wafer parameters

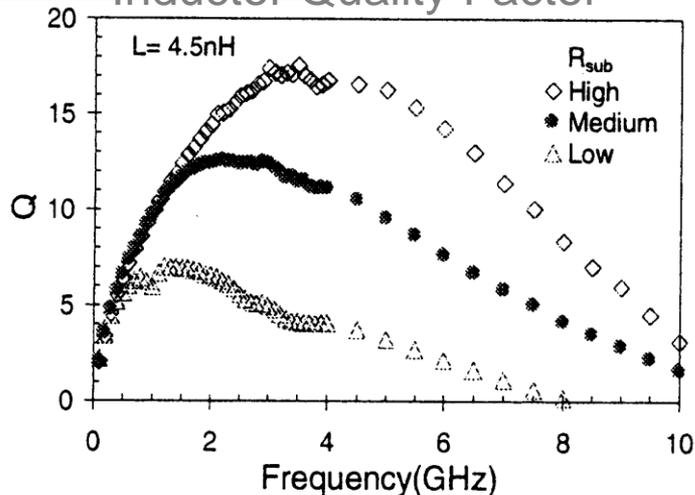
	150mm	200mm	300mm
Diameter	✓	✓	✓

Positive	Cost	Availability
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Negative	Thermal Donors	Extra Design
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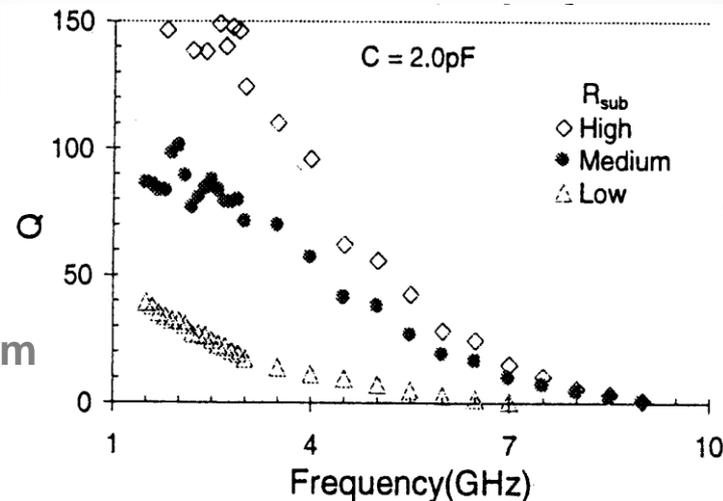
Example Impacts of Resistivity

Inductor Quality Factor

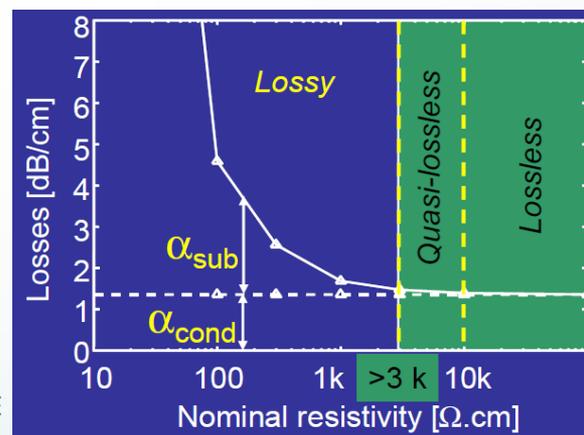
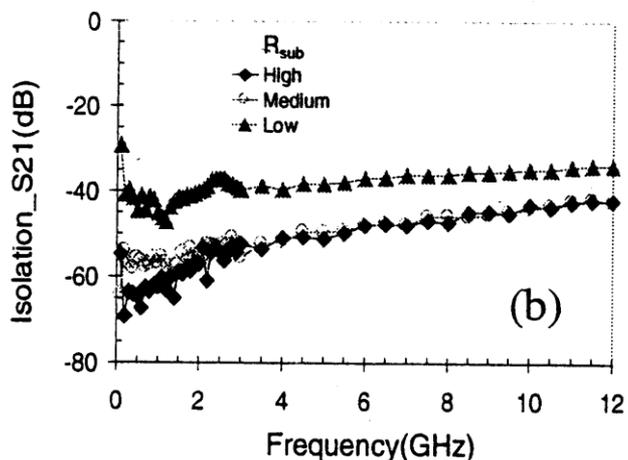


High > 1000 Ωcm
Medium ~ 20-60 Ωcm
Low < 5 Ωcm

Yang, et al,
IEDM2002, 27.8,
pg 667-670.



Cross-talk isolation



J.P. Raskin, IEEE
S3S Conf. 2013



High RF and THz – Si-based

IEDM 2022, Paper 11.7 (ST Microelectronics):

- 130nm bulk HiRes SiGe BiCMOS (ft 230GHz / fmax 280GHz) with low Ron-Coff and high power handling for WiFi 6E RF front end module.
- Complementary to RFSOI w/intent is to offer non-SOI RF FEM for cost sensitive 6G applications while improving power efficiency and better noise figure.
- RFSOI supports WiFi FEM to 2.5GHz, but SiGe enables WiFi FEM to 6GHz.
- Evaluated 1kohm-cm vs 125ohm-cm substrates and prefer 125ohm-cm as more practical and good enough, less prone to latch-up, and easier to acquire with fewer use challenges.
- Higher parasitic capacitance than SOI (absence of BOX) limits power handling. “RFSOI is king for high end front end module”

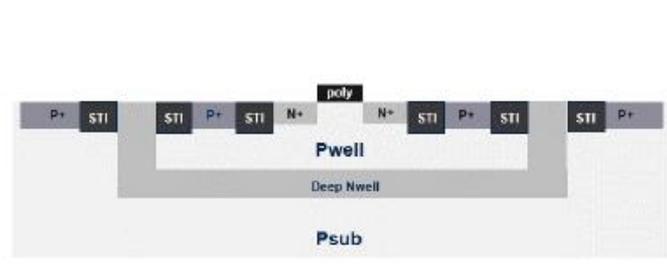


Fig. 1. Triple well device architecture

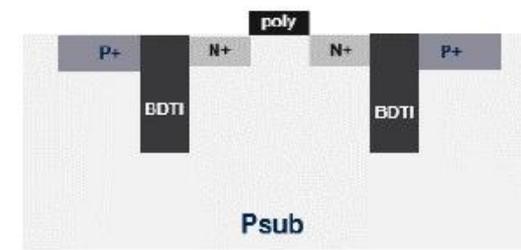


Fig. 2. DTI isolated NMOS architecture

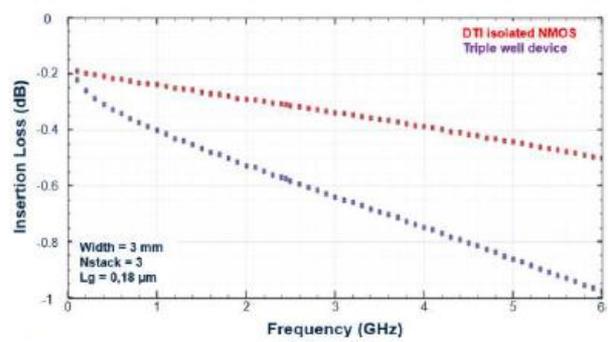


Fig. 3. Comparison of insertion loss of triple well vs DTI isolated NMOS

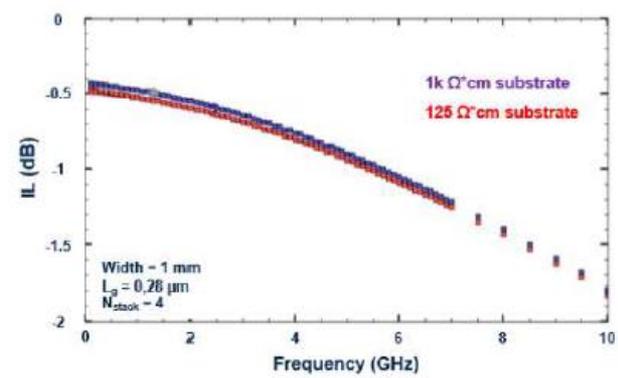


Fig. 4. Substrate resistivity impact on achievable insertion loss

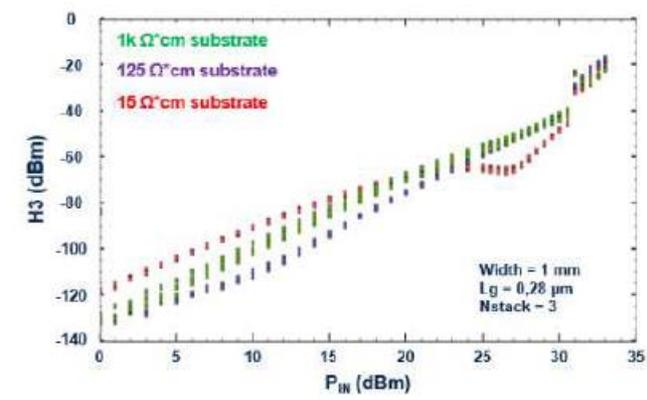


Fig. 5. Substrate resistivity impact on achievable 3rd harmonics in OFF state



Polished Wafers – FZ Silicon

- (100) or (111) highly doped wafers (>1k ohm.cm, Max 50k ohm.cm)
- FZ Crystal Growth

- GHz & THz applications
- RF MEMS switches
- High-Q inductors and capacitors
- GHz Transmitter and receiver circuits
- GHz mixers
- GHz Power amplifiers
- Low loss microstrip transmission lines and coplanar waveguides
- Micromachined thin Film Bulk Acoustic Resonators (FBAR)

Growth method	Hires™ Float Zone Silicon
Resistivity	>1 kΩcm (max resistivity 50 kΩcm)
Resistivity tolerance	±30 - ±50%
Radial resistivity variation	<50 - <60%
Diameter	150-200 mm
Crystal orientation	<100>, <111>*
Type and Dopant	N, P: Undoped
Oxygen and Carbon concentration	<10 ¹⁶ cm ⁻³
Wafer thickness	>200-1300 μm depending on wafer diameter
Wafer surface finish	Single side polished and double side polished

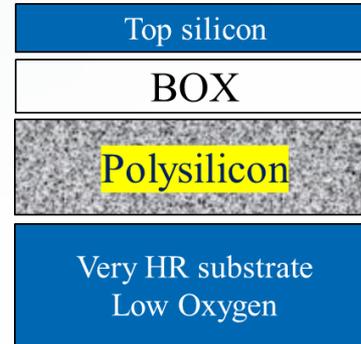
	150mm	200mm	300mm
Diameter	✓	✓	

Positive	Very High Resistivity	
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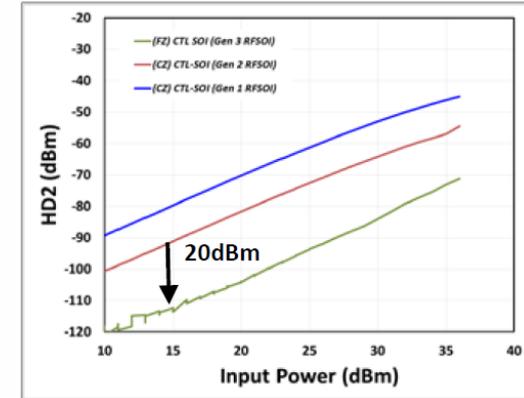
Negative	Cost	Not available on 300mm
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SOI for RF

- Hi-Resistivity handles
- CTL – Charge Trap Layer
 - Switches
 - Power Amplifier



Typical RFSOI wafer



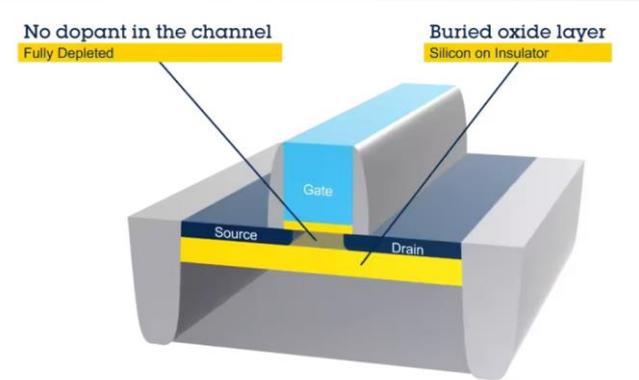
HD2 vs Pin for FZ CTLSOI wafers compared to CZ CTL SOI wafers

	150mm	200mm	300mm
Diameter		✓	✓

Positive	Harmonics Performance	Availability	Top wafer reuse
Negative	Tuning of thermal cycles (Thermal donors, slip lines)	Cost	

SOI for RF - FDSOI

- Very thin Box and Top layers
 - mmWave Front-End
 - SatCom
 - Radar
 - Automotive



Source: ST Microelectronics

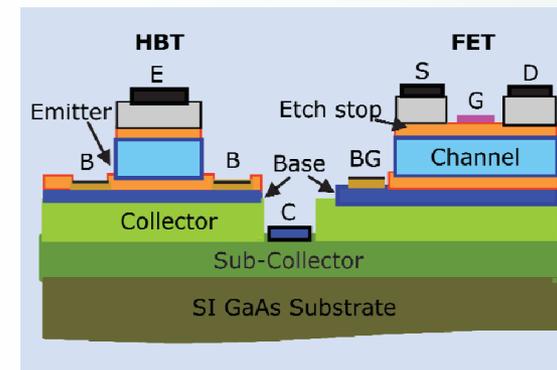
	150mm	200mm	300mm
Diameter			✓

Positive	Digital / Mixed Signal Integration	Back Bias Capability	Low Power Consumption
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Negative	Design Complexity ? Challenging wafer specification	Cost
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GaAs for RF

- For RF typically bulk GaAs semi-insulating crystal with MOCVD grown III-V epi stack
- There has been research for GaAs on Si



	150mm	200mm	300mm
Diameter	✓		

Positive	Output Power Frequency	Low Noise
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Negative	Integration	Cost
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GaN for RF

- Si handle – High Resistivity
(or Semi-Insulating SiC substrate)
- GaN Growth
- GaN on SI-SiC is well established for defense and high temperature applications.
- GaN on HiRes Si(111) is competing in consumer and cost sensitive communication markets

	150mm	200mm	300mm
Diameter	✓	✓	

Positive	Output Power	Frequency
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Negative	Integration	Cost
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GaN Epi on Si(111): Wafer Requirements

MOCVD growth:
150/200mm
capability at GWC

Silicon thickness used
to offset Stress / Bow
from ~ 50% Thermal
Expansion Mismatch.
150mm~1mm, 200mm
~ 1.15mm



Edge profile to prevent
Ga contact to Si and
reduce film cracks,
reduce damage from
susceptor contact,
and for optimum
shape after backgrind

Increase wafer slip resistance
through doping level, oxygen,
co-doping with N

(111) orientation for better
symmetry match to h-GaN

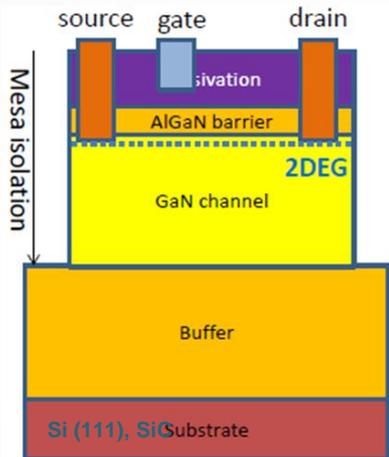
~ 20% lattice mismatch
between Si and GaN...high
dislocation density

Control of slicing orientation
target and tolerance, varies
from spec to spec

P+, P++ for Power GaN
provides better shape control

High resistivity > ~3kohm-cm
for RF GaN/Si

Semi-insulating SiC for RF
GaN/SiC



HEMT = Lateral FET

Power – RF GaN on Si



IEDM 2022 Paper 35.1 (Intel): 300mm GaN on Si(111) HRS for high performance RF power. Record high f_{max} of 680GHz demonstrated for 30nm channel length enhancement mode transistor. Field plating optimized to extend breakdown voltage and reliability from 12V to 40V range operation. Power FOM ($R_{on} \cdot Q_{gg}$) 30X better than Si-LDMOS and 20x better than e-mode p-GaN HEMT.

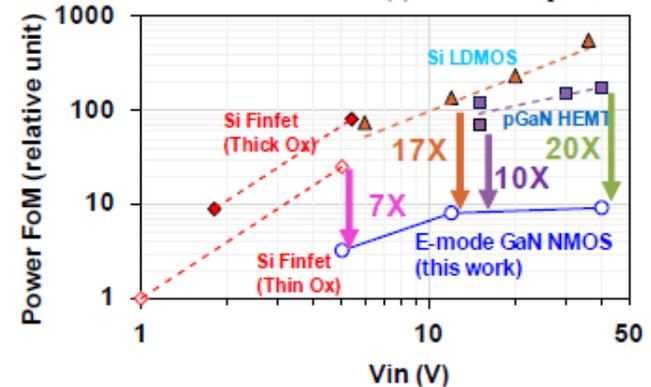
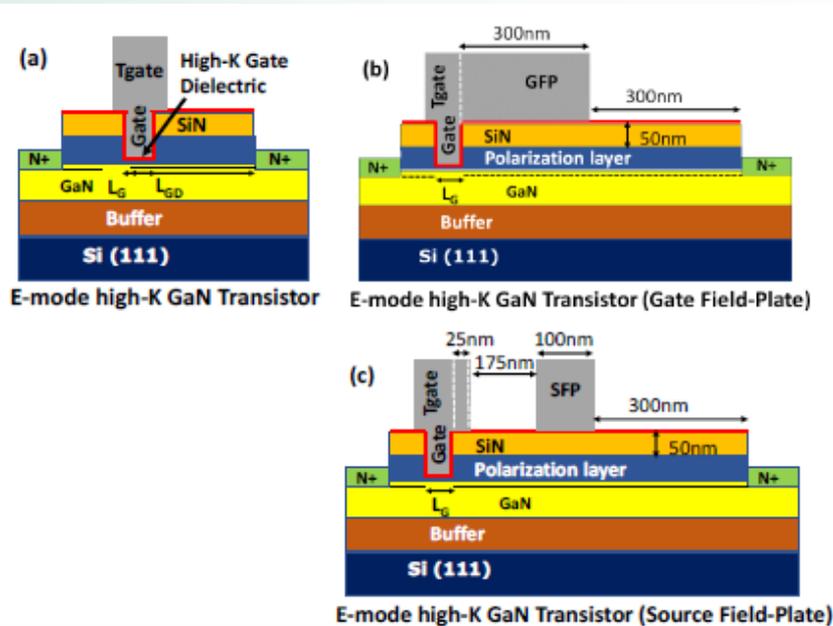


Fig.11 benchmarks the power FoM of the e-mode GaN NMOS of this work, showing ~20X better performance than pGaN HEMT and ~30X better than Si LDMOS at 40V; 10-17X better than Si LDMOS and pGaN HEMT at 12-15V, and 7X better than Si Finfet at 5V.

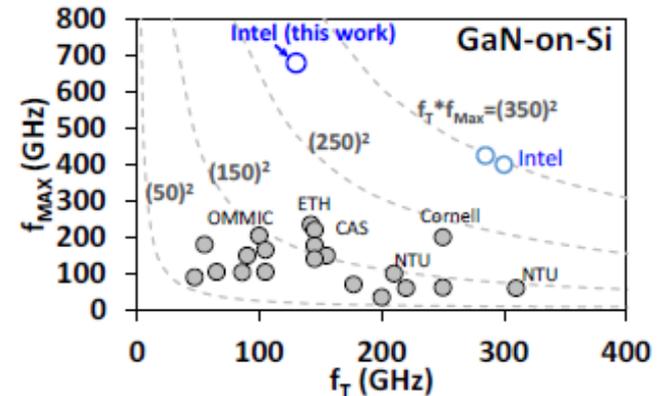


Fig.16 benchmarks the f_T/f_{MAX} of this work with data points reported [13] for GaN-on-Si transistors, showing record $f_{MAX}=680$ GHz with $f_T=130$ GHz, shown in Fig.12. Intel data points are the only ones from 300nm GaN-on-Si(111) process.



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